

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

	Sylvia H. Pas	Examiner: TBD
Serial No:	TBD	Art Unit: TBD
Filed:	01/11/01	Docket No.: TI-22398
For:	SYSTEM AND METHOD FOR INTEGRATED OXIDE REMOVAL AND PROCESSING OF A SEMICONDUCTOR WAFER	

PRELIMINARY AMENDMENT

January 11, 2001

Assistant Commissioner for Patents

Washington, DC 20231

Dear Sir:


Please amend the above referenced application as follows:

In the Specification:

Page 1, before line 1, insert --This application claims priority under 35 USC §  
119(e)(1) of provisional application numbers **60/178,647** filed **01/28/00**.--

[illegible]

If the Examiner has any questions or other correspondence regarding this application, Applicant requests that the Examiner contact Applicant's attorney at the below listed telephone number and address.

  
Jacqueline J. Garner

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